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Attorney Docket No. 033082 M 301

P A T E N T

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:) **CONFIRMATION NO.: 2808**
)
) **Sumi TANAKA, et al.**
)
U.S. Serial No.: 10/568,683) Group Art Unit: 1763
)
Filed: February 17, 2006) Examiner: Matthew T. Eggerding

For: SUBSTRATE HOLDING STRUCTURE AND SUBSTRATE PROCESSING APPARATUS

RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir :

A response to the Office Action mailed June 15, 2007 is due by July 15, 2007. The Action required restriction between two (Groups I and II) patentably distinct inventions.

Applicants hereby elect Group I of claims 1-9, drawn to a substrate holding structure and processing apparatus, for examination in this application. Applicants advise that no change in the inventorship of the application will be required by the eventual cancellation of non-elected claims.

Applicants reserve the right to file divisional application(s) for the non-elected claims in due course.

It is submitted that this application now is in condition for examination on the merits and early action in that regard is solicited.

Respectfully submitted,

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